Fig.1A

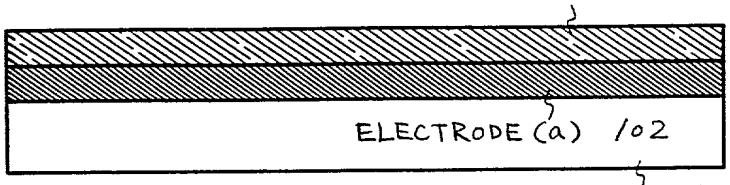


Fig.1B: PLASMA PROCESSING STEP

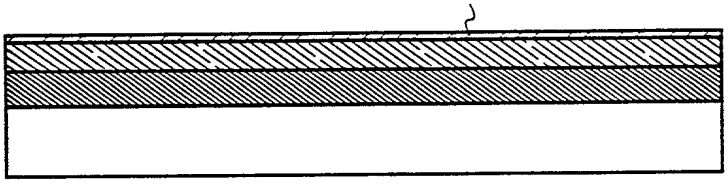


Fig.1C

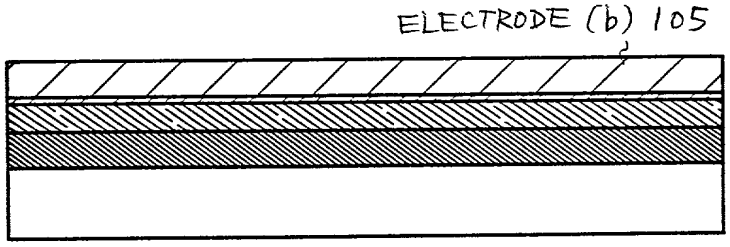


Fig.1D

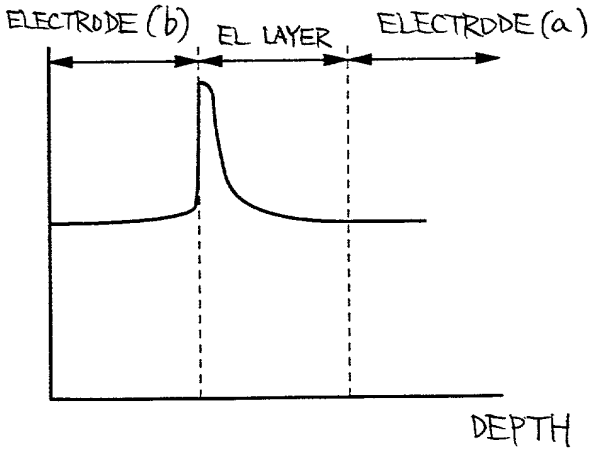


Fig. 2A

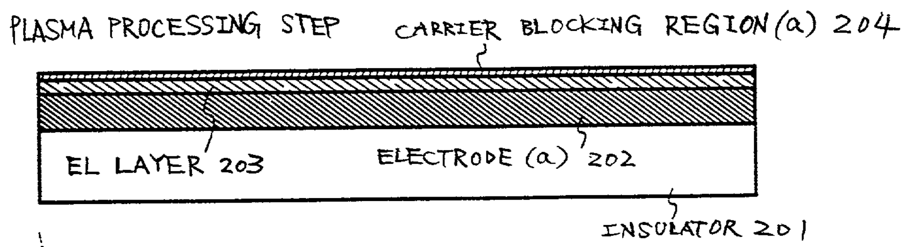


Fig. 2B

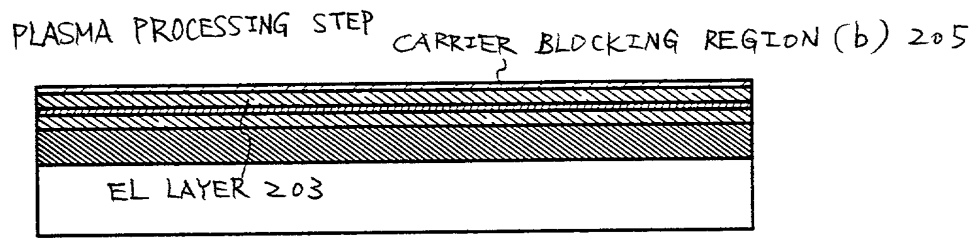


Fig. 2C

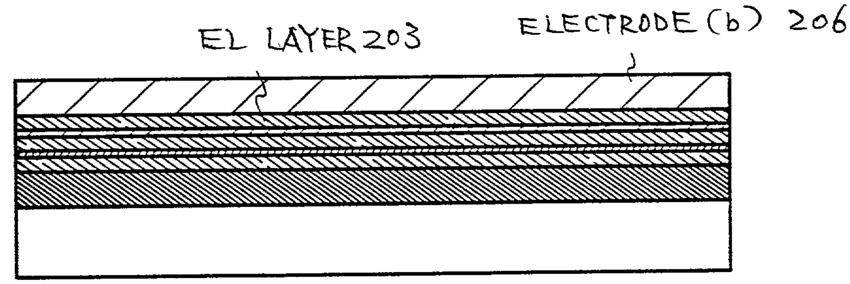


Fig. 3A

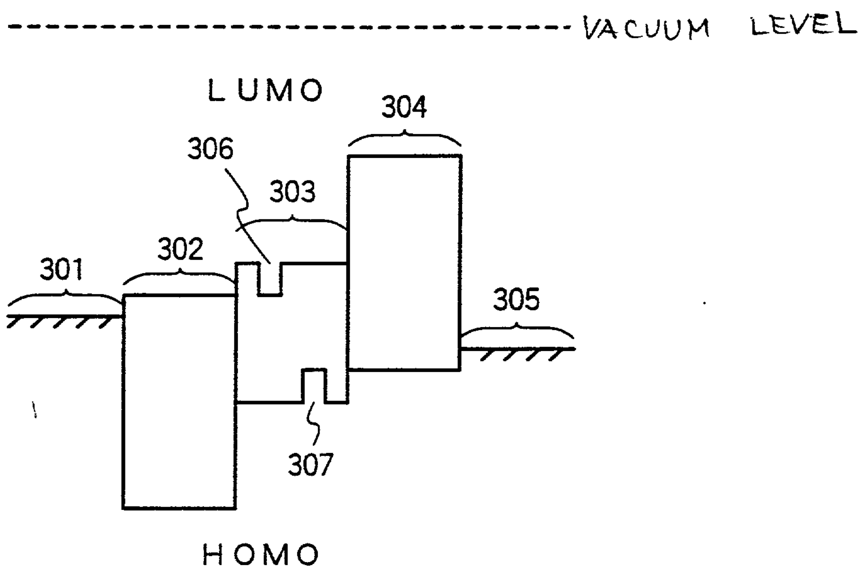


Fig. 3B

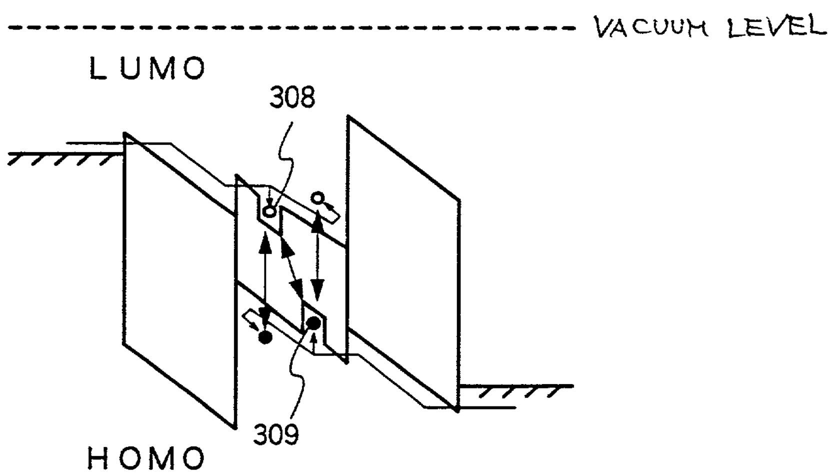


Fig. 4A

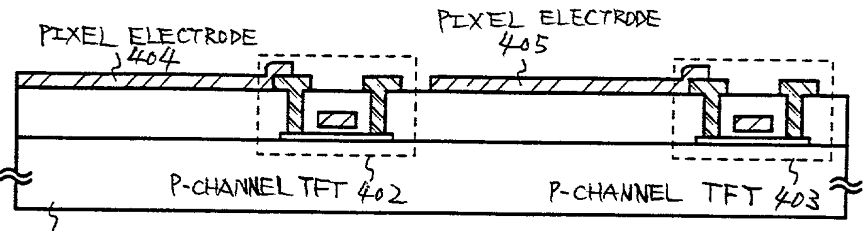


Fig. 4B

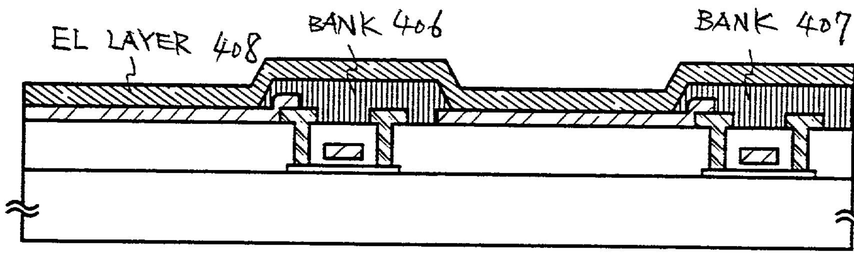


Fig. 4C

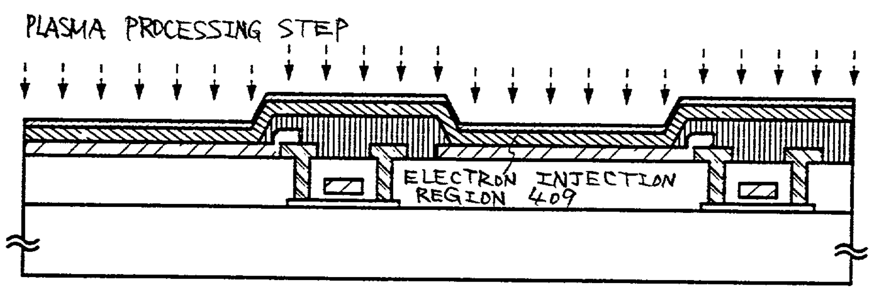


Fig. 4D

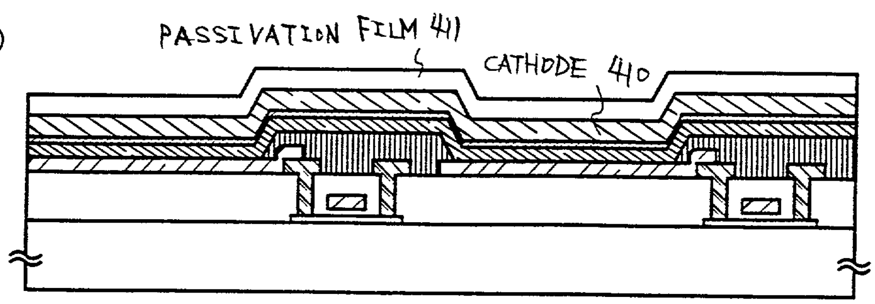


Fig. 5A

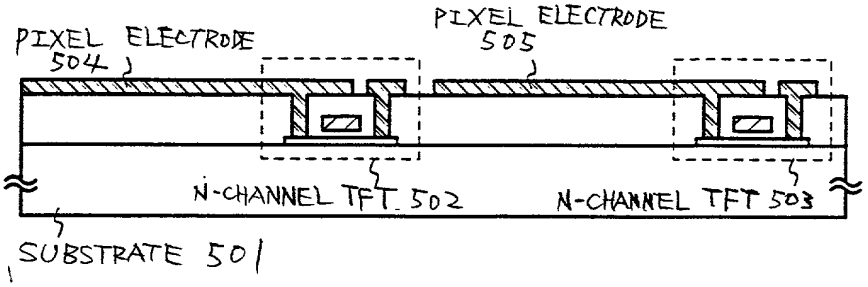
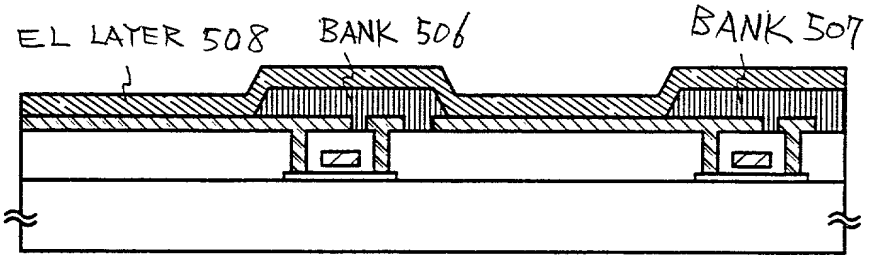


Fig. 5B



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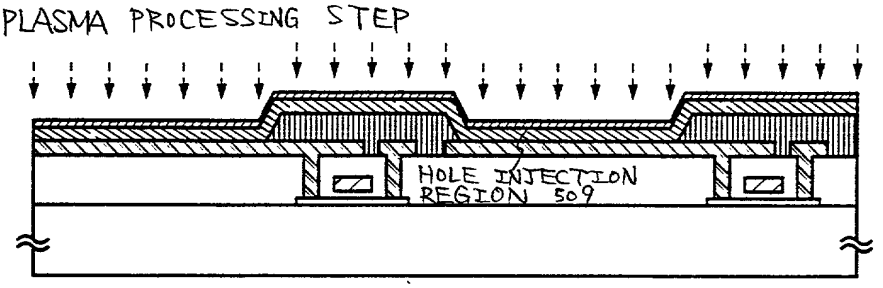


Fig. 5D

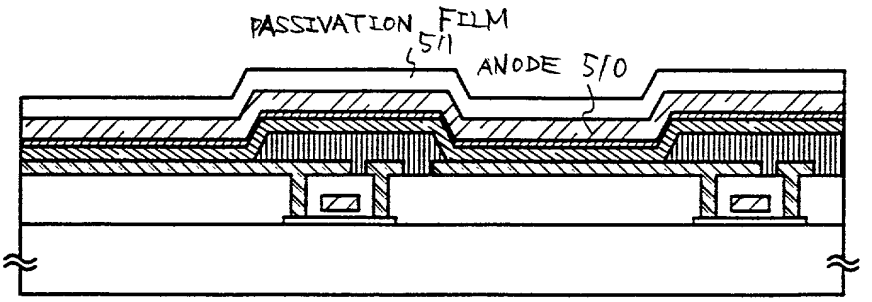


Fig. 6A

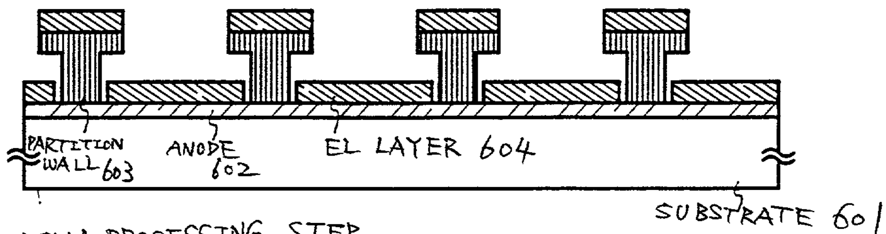


Fig. 6B

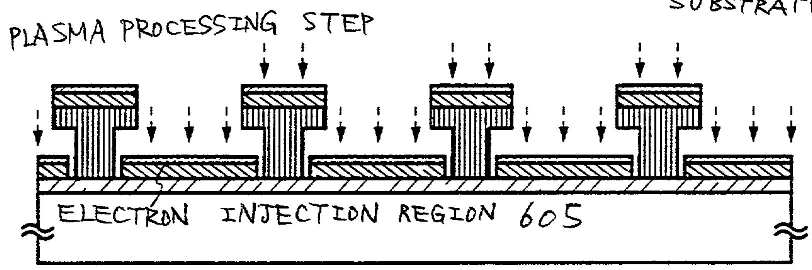


Fig. 6C

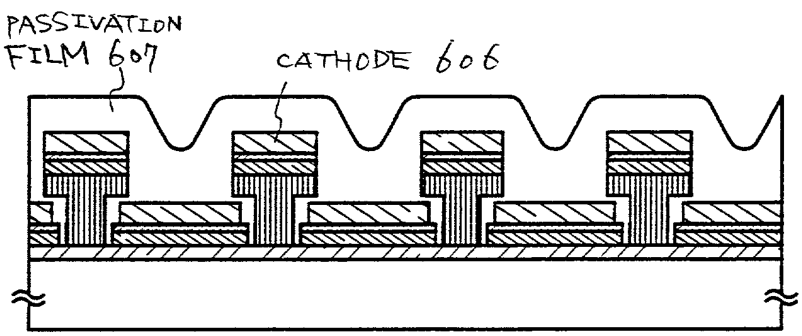


Fig. 7A

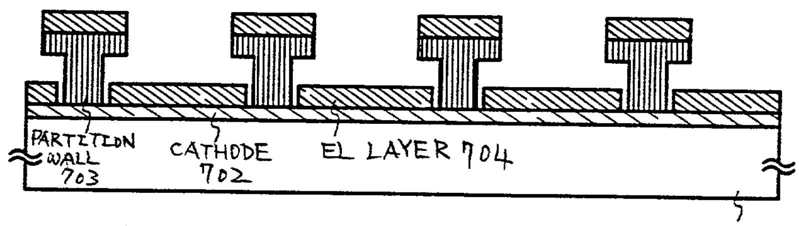


Fig. 7B

PLASMA PROCESSING STEP

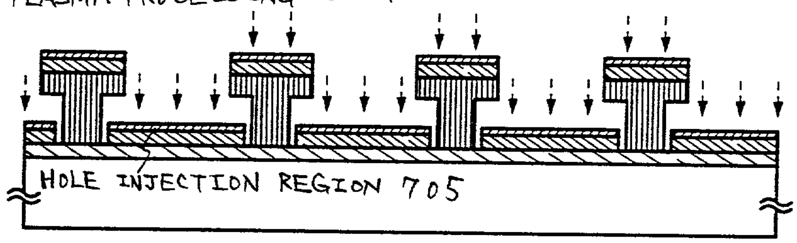
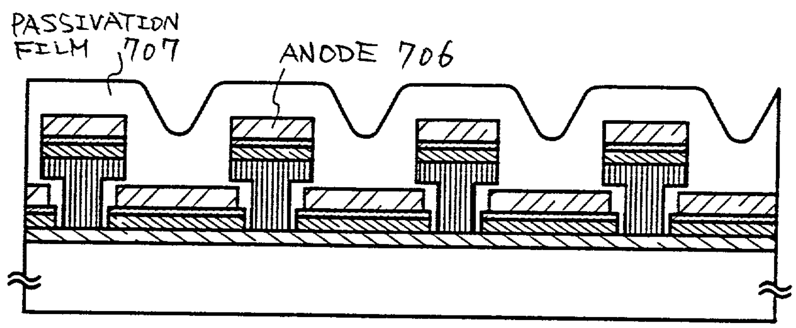


Fig. 7C



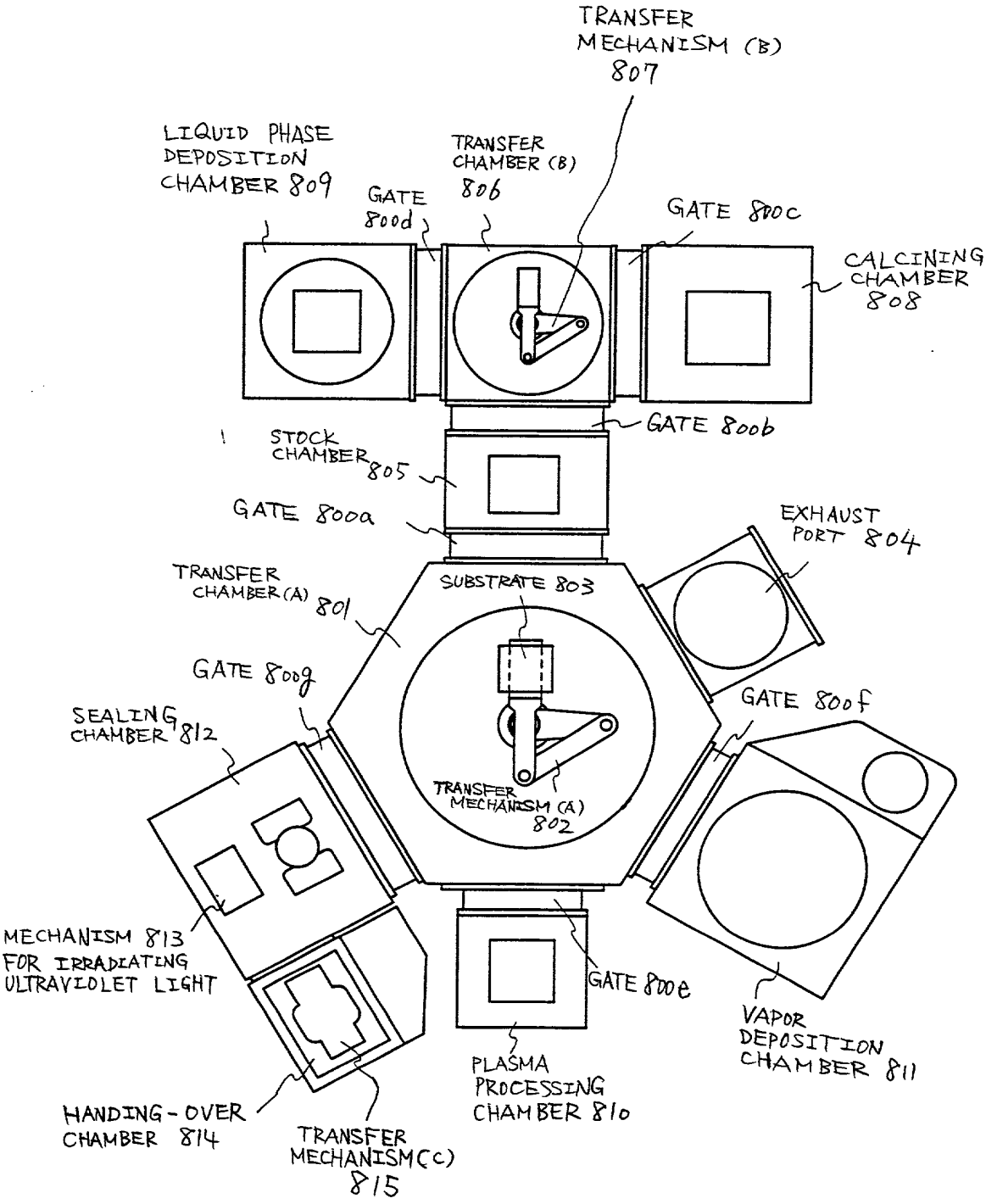

TRANSFER MECHANISM (B) 807
LIQUID PHASE DEPOSITION CHAMBER 809
TRANSFER CHAMBER (B) 806
GATE 800d
GATE 800c
CALCINING CHAMBER 808
GATE 800b
STOCK CHAMBER 805
GATE 800a
EXHAUST PORT 804
TRANSFER CHAMBER (A) 801
SUBSTRATE 803
GATE 800g
GATE 800f
SEALING CHAMBER 812
TRANSFER MECHANISM (A) 802
MECHANISM 813 FOR IRRADIATING ULTRAVIOLET LIGHT
GATE 800e
VAPOR DEPOSITION CHAMBER 811
PLASMA PROCESSING CHAMBER 810
HANDING-OVER CHAMBER 814
TRANSFER MECHANISM(C) 815

Fig. 8

Fig. 9A

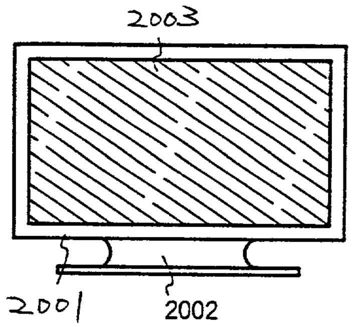


Fig. 9B

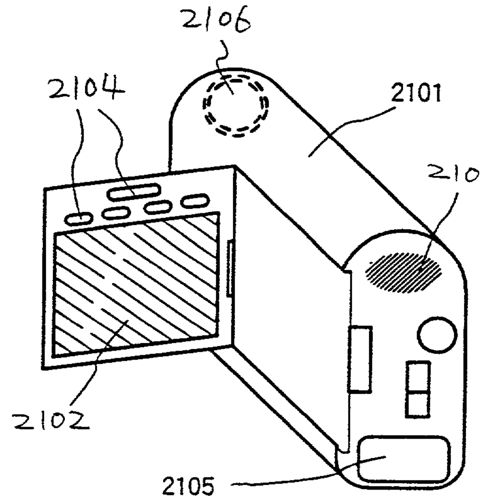


Fig. 9C

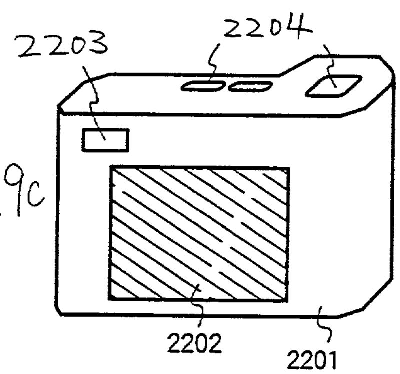


Fig. 9D

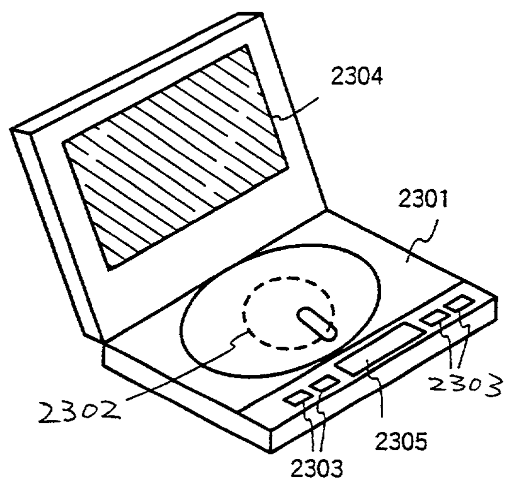


Fig. 9E

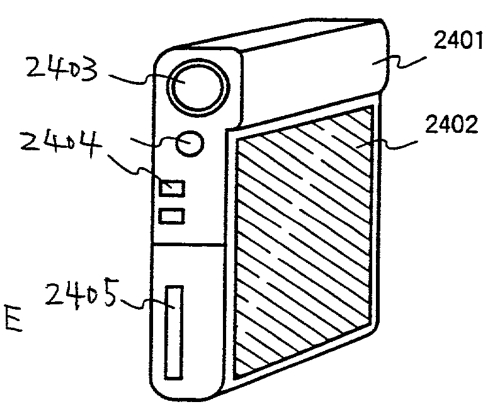
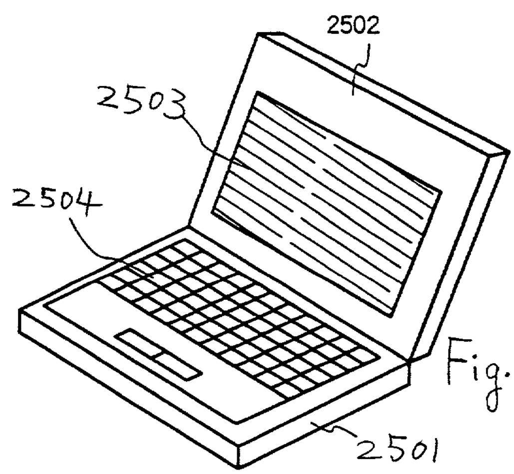


Fig. 9F



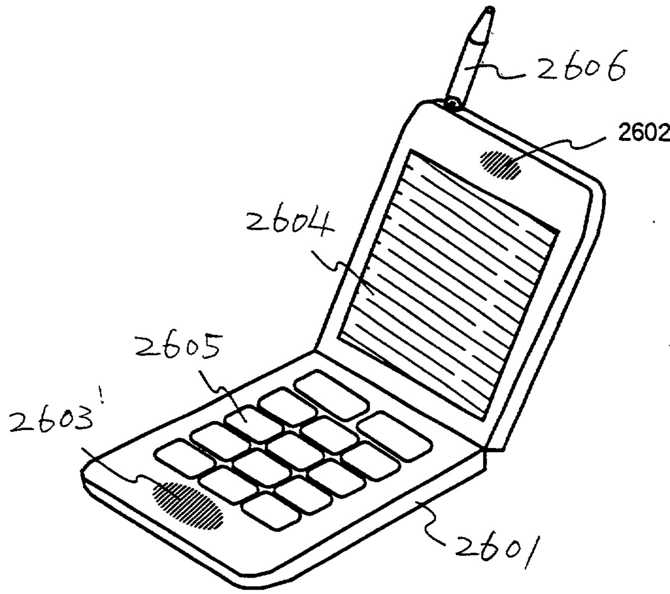


Fig. 10A

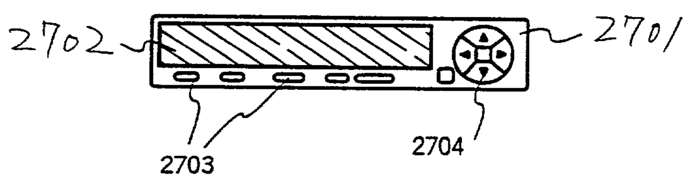


Fig. 10B